## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	Group Art Unit: 1792
Yonhua Tzeng	Examiner: Stouffer, Kelly M.
Serial No.: 10/772,740	
Filed: February 5, 2004	AMENDMENT AND REQUEST FOR CONTINUED EXAMINATION (RCE)
For: METHOD OF PLASMA ENHANCED CHEMICAL VAPOR DEPOSITION OF DIAMOND USING METHANOL-BASED SOLUTIONS	162 North Wolfe Road Sunnyvale, California 94086 (408) 530-9700
ý	Customer No.: 28960

Mail Stop RCE Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

## **AMENDMENTS**

Sir:

Please amend the subject application as follows:

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.